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*Hobart, K.D.; Kub, F.J.; Jernigan, G.G.; Twigg, M.E.; Thompson, P.E.;*

Electronics Letters, Volume: 34, Issue: 12, 11 June 1998

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**2 Ultra-cut: a simple technique for the fabrication of SOI substrates with ultra-thin (<5 nm) silicon films**

*Hobart, K.D.; Kub, F.J.; Twigg, M.E.; Jernigan, G.G.; Thompson, P.E.;*

SOI Conference, 1998. Proceedings., 1998 IEEE International, 5-8 Oct. 1998

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**3 SOI on buried cavity patterns using ion-cut layer transfer**

*Yun, C.H.; Cheung, N.W.;*

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**4 CMOS on bonded wafers fabricated using a novel Si-Ge etch stop**

*King, E.E.; Huang, D.H.; Leonov, P.; Palkuti, L.J.; Campisi, G.J.; Hughes, H.L.; Godbey, D.J.;*

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**5 A new method of forming a thin single-crystal silicon diaphragm using merged epitaxial lateral overgrowth for sensor applications**

*Pak, J.J.; Neudeck, G.W.; Kabir, A.E.; DeRoo, D.W.; Staller, S.E.;*

Electron Device Letters, IEEE, Volume: 12, Issue: 11, Nov. 1991

Pages:614 - 616

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**6 Highly uniform SOI fabrication by applying voltage during KOH etching of bonded wafers**

*Ogura, A.;*

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**7 Silicon-on-quartz for low power electronic applications**

*Sarma, K.R.; Liu, S.T.;*

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**8 Novel high-performance pressure sensors using double SOI structures**

*Chung, G.-S.; Kawahito, S.; Ashiki, M.; Ishida, M.; Nakamura, T.;*

Solid-State Sensors and Actuators, 1991. Digest of Technical Papers,

TRANSDUCERS '91., 1991 International Conference on , 24-27 June 1991

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**9 A trench isolated SOI bipolar process**

*Shain, D.; Badilo, R.;*

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